

## INTERNATIONAL SEARCH REPORT

International Application No  
PCT/DE2005/000059

A. CLASSIFICATION OF SUBJECT MATTER  
IPC 7 C23C14/34 C23C14/08

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)  
IPC 7 C23C

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)  
EPO-Internal, INSPEC, PAJ

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	KON M ET AL: "IMPEDANCE CONTROL OF REACTIVE SPUTTERING PROCESS IN MID-FREQUENCY MODE WITH DUAL CATHODES TO DEPOSIT AL-DOPED ZNO FILMS" JAPANESE JOURNAL OF APPLIED PHYSICS, PUBLICATION OFFICE JAPANESE JOURNAL OF APPLIED PHYSICS. TOKYO, JP, vol. 42, no. PART 1, 1, January 2003 (2003-01), pages 263-269, XP001090514 ISSN: 0021-4922 paragraphs '0002!, '0003!; figures 2,4,11	1-6
Y		7,15,16 -/-

Further documents are listed in the continuation of box C.

Patent family members are listed in annex.

## • Special categories of cited documents :

- \*A\* document defining the general state of the art which is not considered to be of particular relevance
- \*E\* earlier document but published on or after the International filing date
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Date of the actual completion of the international search

15 August 2005

Date of mailing of the international search report

29/08/2005

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## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	S. JAEGER ET AL: "Comparison of transparent conductive oxide thin films prepared by a.c. and d.c. reactive magnetron sputtering" SURFACE AND COATINGS TECHNOLOGY, vol. 98, no. 1-3, 1 January 1998 (1998-01-01), pages 1304-1314, XP002338603 ch paragraph '03.3!; figure 11; table 4	8-14
Y	PATENT ABSTRACTS OF JAPAN vol. 2003, no. 07, 3 July 2003 (2003-07-03) & JP 2003 068643 A (JAPAN ADVANCED INST OF SCIENCE & TECHNOLOGY HOKURIKU), 7 March 2003 (2003-03-07) abstract	7,15,16
Y	PATENT ABSTRACTS OF JAPAN vol. 015, no. 453 (E-1134), 18 November 1991 (1991-11-18) & JP 03 191578 A (MITSUBISHI ELECTRIC CORP), 21 August 1991 (1991-08-21) abstract	15
A	BOSE S ET AL: "TEXTURED ALUMINIUM-DOPED ZNO THIN FILMS PREPARED BY MAGNETRON SPUTTERING" JOURNAL OF PHYSICS D. APPLIED PHYSICS, IOP PUBLISHING, BRISTOL, GB, vol. 29, no. 7, 14 July 1996 (1996-07-14), pages 1873-1877, XP000621105 ISSN: 0022-3727 figures 5,6	16
A	CHANG J F ET AL: "The effect of deposition temperature on the properties of Al-doped zinc oxide thin films" THIN SOLID FILMS, ELSEVIER-SEQUOIA S.A. LAUSANNE, CH, vol. 386, no. 1, 1 May 2001 (2001-05-01), pages 79-86, XP004230504 ISSN: 0040-6090 paragraph '0002!; table 2	1-16

## INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No

PCT/DE2005/000059

Patent document cited in search report	Publication date	Patent family member(s)		Publication date
JP 2003068643	A 07-03-2003	NONE		
JP 03191578	A 21-08-1991	JP 2673021 B2		05-11-1997